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INFORMATION DISCLOSURE STATEMENT  (Use several sheets if necessary)				APPLICANTS Masahiro SAKURADA et al.			
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U.S. PATENT DOCUMENTS						
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	

  

FOREIGN PATENT DOCUMENTS						
DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS		
<i>FH</i> 1 WO 97/21853 w/abstract	06/19/1997	WIPO				
<i>FH</i> 2 JP A 2000-53486 w/abstr.	02/22/2000	Japan				
<i>FH</i> 3 JP A 5-43385 w/abstr. + trans.	02/23/1993	Japan				
<i>FH</i> 4 JP A 9-227286 w/abstr. + trans.	09/02/1997	Japan				

  

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)				
<i>FH</i>	5	Voronkov, "The Mechanism of Swirl Defects Formation in Silicon," Journal of Crystal Growth, Vol. 59, No. 3, pp. 625-643, 1982		
<i>FH</i>	6	Dupret et al., "Global modeling of heat transfer in crystal growth furnaces," Int. J. Heat Mass. Transfer, Vol. 33, No. 9, pp. 1849-1871, 1990		
<i>FH</i>	7	Vizman et al., "Three-dimensional numerical simulation of thermal convection in an industrial Czochralski melt: comparison to experimental results," Journal of Crystal Growth 233, pp. 687-698, 2001		

  

EXAMINER <i>[Signature]</i>	DATE CONSIDERED <i>8/2/06</i>
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Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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